

Title (en)
Vacuum pump

Title (de)
Vakuumpumpe

Title (fr)
Pompe à vide

Publication
EP 1201927 B1 20040901 (EN)

Application
EP 01124365 A 20011023

Priority
JP 2000322577 A 20001023

Abstract (en)
[origin: EP1201927A2] A main body of a multi-stage Roots pump 11 is incorporated in a cover 47. A connecting flange 39, a muffler 40, a guide pipe 41 and a discharge pipe 42 constitute a discharge piping mechanism 64. The discharge pipe 42 incorporates a bellows 421. A connecting flange 58 and a suction pipe 59 constitute a suction piping mechanism 65. The suction pipe 59 incorporates a bellows 591. The bellows 421, 591 are incorporated in the cover 47. Thus, loads generated when the bellows constituting part of the gas flow path of a vacuum pump are elastically deformed, by virtue of changes in internal pressures, are prevented from extending to auxiliary equipment. <IMAGE>

IPC 1-7
F04C 18/12; **F04C 29/08**

IPC 8 full level
F04C 25/02 (2006.01); **F04B 37/16** (2006.01); **F04C 18/12** (2006.01); **F04C 29/06** (2006.01); **F04C 29/12** (2006.01)

CPC (source: EP)
F04C 18/126 (2013.01); **F04C 29/065** (2013.01); **F04C 29/12** (2013.01)

Cited by
EP1900943A1; CN102297135A; EP1398506A3; EP1396636A3; CN1330879C; EP1479913A3; EP1398507A3; CN104131962A; US7108492B2; US7364414B2; EP1398506A2; US7255541B2

Designated contracting state (EPC)
DE FR GB

DOCDB simple family (publication)
EP 1201927 A2 20020502; **EP 1201927 A3 20030122**; **EP 1201927 B1 20040901**; DE 60105249 D1 20041007; DE 60105249 T2 20050901; JP 2002130170 A 20020509

DOCDB simple family (application)
EP 01124365 A 20011023; DE 60105249 T 20011023; JP 2000322577 A 20001023